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(71) Applicant: **LAM RESEARCH CORPORATION**
[US/US]; 4650 Cushing Parkway, Fremont, California
94538 (US).

(72) Inventors: **KWON, Byung Seok**; 4650 Cushing Park-
way, Fremont, California 94538 (US). **NGUYEN, Bryan**;
4650 Cushing Parkway, Fremont, California 94538 (US).
WANG, Ruisong; 4650 Cushing Parkway, Fremont, Cal-
ifornia 94538 (US). **YIN, Xin**; 4650 Cushing Parkway,
Fremont, California 94538 (US). **HA, Jeongseok**; 4650
Cushing Parkway, Fremont, California 94538 (US). **HAM-**
MA, Soumana; 4650 Cushing Parkway, Fremont, Califor-

nia 94538 (US). **SHAIKH, Fayaz A.**; 4650 Cushing Park-
way, Fremont, California 94538 (US).

(74) Agent: **HALL, Matt**; Alleman Hall & Tuttle LLP, 900 SW
5th Ave., Suite 2300, Portland, Oregon 97204 (US).

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(54) Title: PROCESSING CHAMBER PRECOAT WITH TRAPPING LAYER AND SEALING LAYER

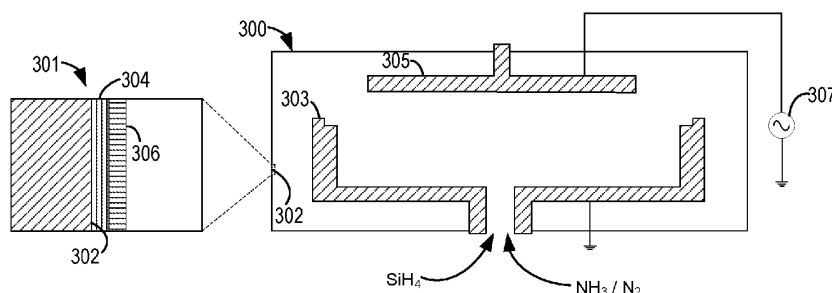


FIG. 3C

(57) Abstract: Examples are disclosed that relate to pretreating a processing chamber of a processing tool. One example provides a method for operating a processing tool. The method comprises, in a preprocessing phase, depositing an undercoat layer on interior surfaces within a processing chamber of the processing tool. The method further comprises, in the preprocessing phase, depositing a precoat layer by performing one or more precoat cycles. Each precoat cycle comprises depositing a trapping layer on the interior surfaces within the processing chamber, the trapping layer comprising a first material. Each precoat cycle further comprises depositing a sealing layer over the trapping layer, the sealing layer comprising a second material different than the first material. The method further comprises, in a processing phase, performing a deposition process on a substrate to deposit a process film on the substrate after depositing the precoat layer.

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